Basic Mechanisms of "Standard" Niobium "EP"

Hui Tian
Charles Reece

SRF Materials Mtg, February 2010

Tutorial in spirit, see published literature for more precise use of language.

Basic Mechanisms of "Standard" Niobium "EP"

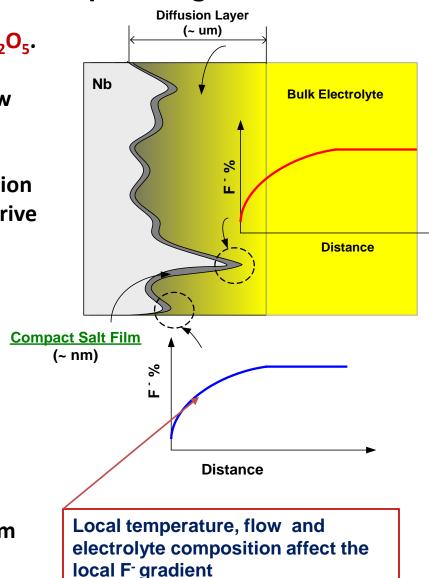


SRF Materials Mtg, February 2010

Tutorial in spirit, see published literature for more precise use of language.

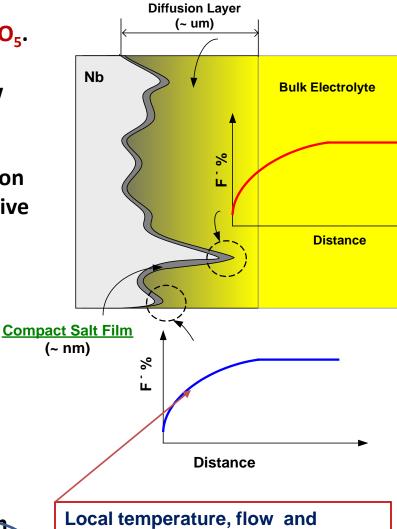
Past studies show that the diffusion-limited access of F⁻ to the salt film produces "best" polishing

- Anodization of Nb in H₂SO₄ forces growth of Nb₂O₅.
- F⁻ dissolves Nb₂O₅.
- These competing processes result in current flow and material removal.
- Above a certain anodization potential, the reaction rate plateaus, limited by how fast fresh F⁻ can arrive at the surface. (diffusion-limited)
- In this steady-state case, this Nb₂O₅ layer is a "compact salt film" with specific resistivity.
- The thickness of the salt film increases with applied potential, although the steady-state current does not change (plateau).
- In the diffusion-limited circumstance, material removal is blind to crystallography (avoids crystallographic etching).
- The diffusion coefficient sets a scale for optimum leveling effects



Past studies show that the diffusion-limited access of F⁻ to the salt film produces "best" polishing

- Anodization of Nb in H₂SO₄ forces growth of Nb₂O₅.
- F⁻ dissolves Nb₂O₅.
- These competing processes result in current flow and material removal.
- Above a certain anodization potential, the reaction rate plateaus, limited by how fast fresh F⁻ can arrive at the surface. (diffusion-limited)
- In this steady-state case, this Nb₂O₅ layer is a "compact salt film" with specific resistivity.
- The thickness of the salt film increases with applied potential, although steady-state current does not change (*plateau*).
- In the diffusion-limited circumstance, material removal is blind to crystallography (avoids crystallographic <u>etching</u>).
- The diffusion coefficient sets a scale for optimum leveling effects.



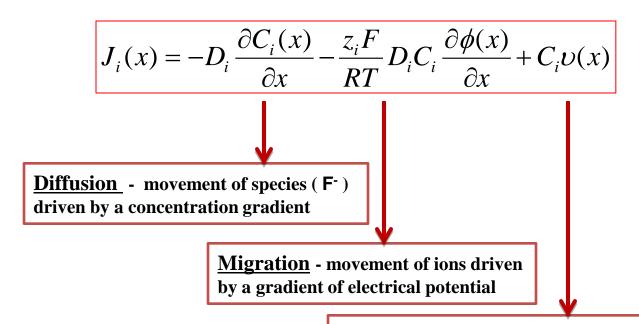
electrolyte composition affect the

local F-gradient

So we want to understand this diffusion coefficient

Current-limited plateau is the result of a mass-transport limitation

Mass transport may occur by three mechanisms in an electrochemical cell. It is described by the Nernst-Planck equation, written for one-dimensional mass transfer along the x-axis as:

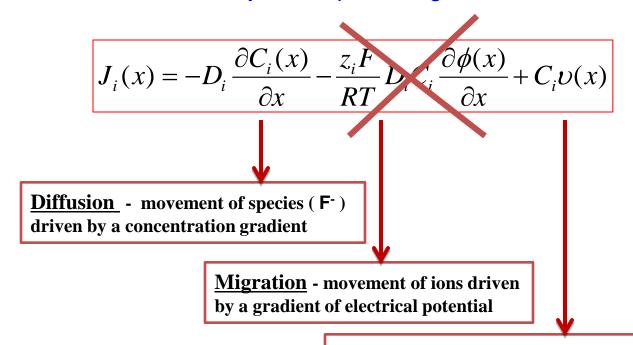


<u>Convection</u> - *natural* convection driven by density gradient and *forced* convection (stirring, vibration, circulation)

Current-limited plateau is the result of mass-transport limitation

Mass transport might occur by three mechanisms in an electrochemical cell. It is described by the Nernst-Planck equation, written for one-dimensional mass transfer along the x-axis as:

If "really" in I-V plateau, gradient at surface must be negligible

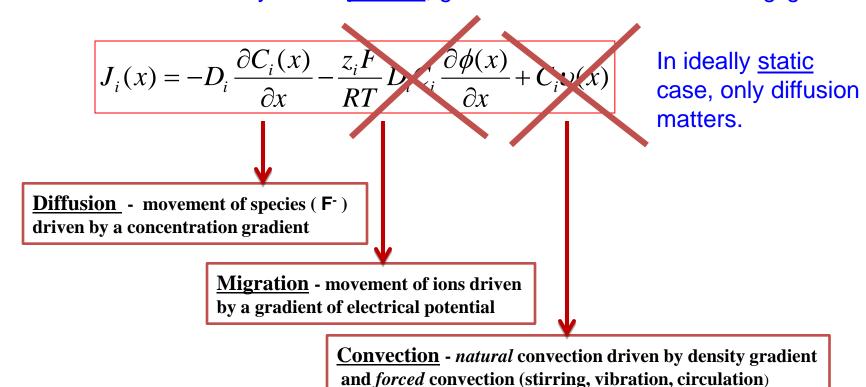


<u>Convection</u> - *natural* convection driven by density gradient and *forced* convection (stirring, vibration, circulation)

Current-limited plateau is the result of mass-transport limitation

Mass transport might occur by three mechanisms in an electrochemical cell. It is described by the <u>Nernst-Planck equation</u>, written for one–dimensional mass transfer along the x-axis as:

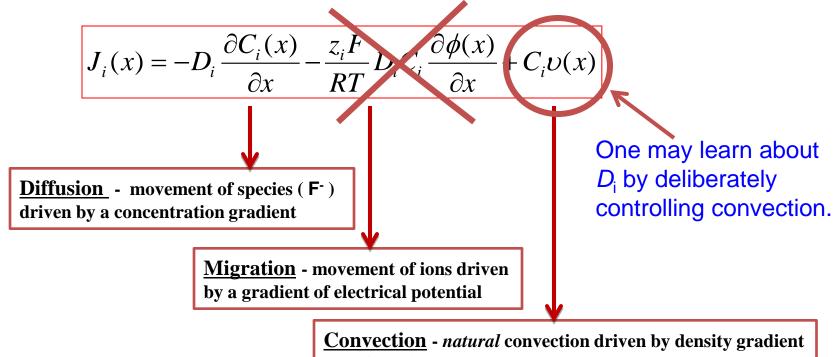
If "really" in I-V plateau, gradient at surface must be negligible



Current-limited plateau is the result of mass-transport limitation

Mass transport might occur by three mechanisms in an electrochemical cell. It is described by the Nernst-Planck equation, written for one-dimensional mass transfer along the x-axis as:

If "really" in I-V plateau, gradient at surface must be negligible



and *forced* convection (stirring, vibration, circulation)

Determination of the limited species diffusion coefficient by rotating disk electrode (RDE)



RDE: creates a defined solution flow pattern in which the mass transport of species is <u>almost completely</u> <u>due to convection</u>. By solving the convection equation with the boundary condition, the Levich equation can be used to describe the relationship of limiting current to the physical properties of electrolyte bath - diffusion coefficient (*D*) and kinematic viscosity (v).

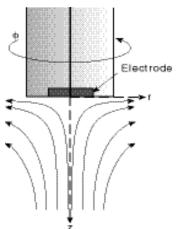


$$J = 0.62nFD^{0.67}v^{-0.166}c\omega^{0.5}$$
$$slope(J vs. \omega^{0.5}) = 0.62nFD^{0.67}v^{-0.166}c$$

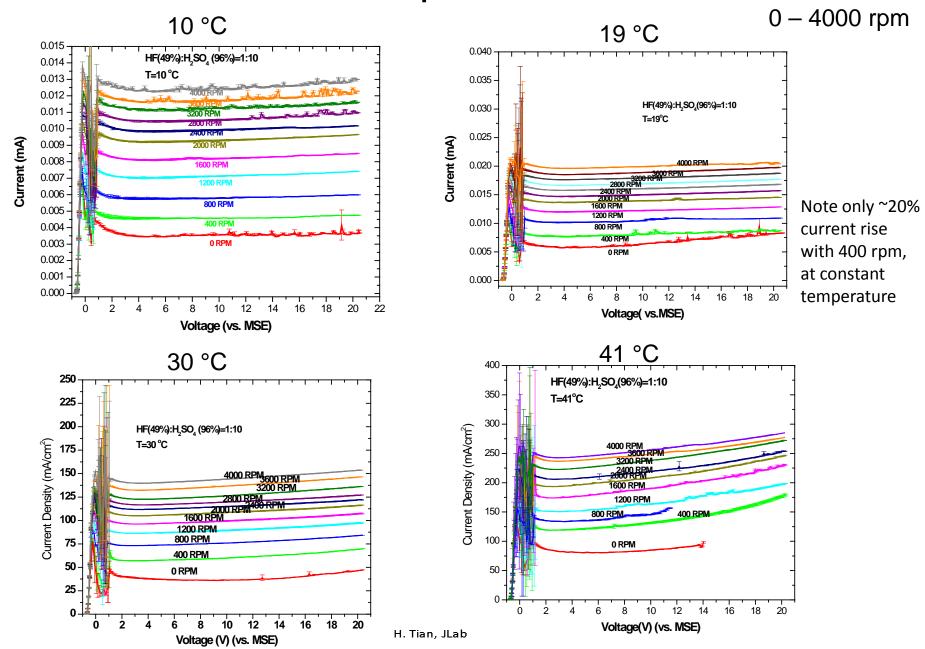
 υ : kinematic vis $\cos ity$

 ω : rotation speed of the electrode

c: concentration of active species

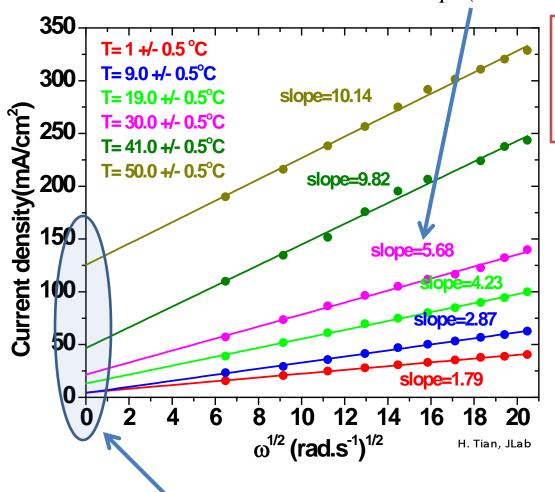


I-V curves of Nb electropolishing at different temperatures with RDE



RDE measurements

 $slope(J vs. \omega^{0.5}) = 0.62 nFD^{0.67} v^{-0.166} c$



Excellent linear fit provides definitive evidence of a diffusion-limited process.

Knowing v and c yields D.

 $c_F = 2.67 \times 10^{-3} \text{ mol/cm}^3$

Strong evidence for temperature-dependent electrochemical etching in parallel with the diffusion-limited process. For analysis, we must separate these current contributions.

Determining Electrolyte Physical Properties

D (cm2/s)

1.5E-07

1.0E-07

5.0E-08

0.0E + 00

0

10

20

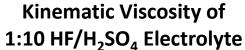
T (°C)

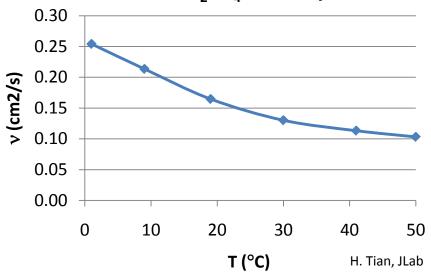
30

40

50

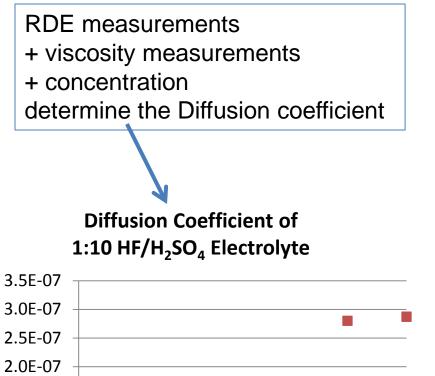
H. Tian, JLab



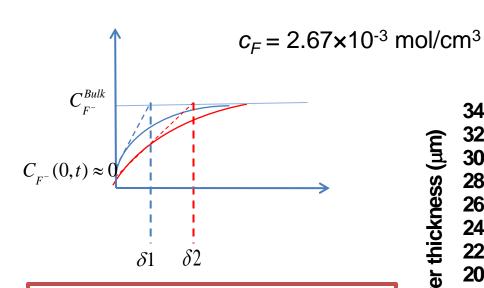


Measured using a Brookfield DV-II pro viscometer

$$c_F = 2.67 \times 10^{-3} \text{ mol/cm}^3$$

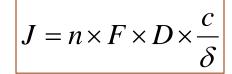


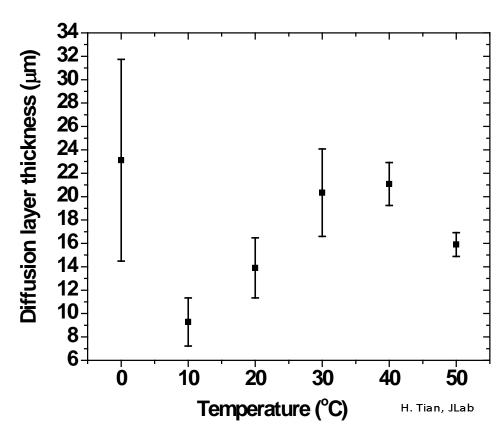
Estimation of diffusion layer thickness in 1:10 HF/H₂SO₄ Electrolyte at different temperatures



There exists a F^- concentration gradient within the 10-20 μ m away from the surface.

On this scale, peaks are dissolved much faster than valleys.



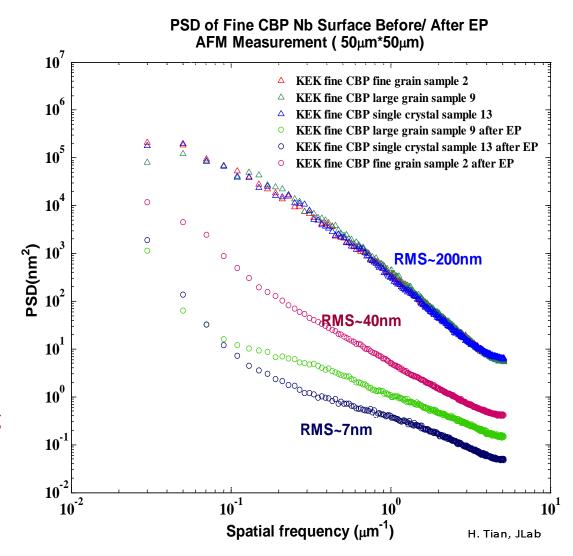


Not all Nb "EPs" the same

With "standard" 1:10 HF/H₂SO₄ Electrolyte at 30°C Nb crystallography affects the polishing effectiveness.

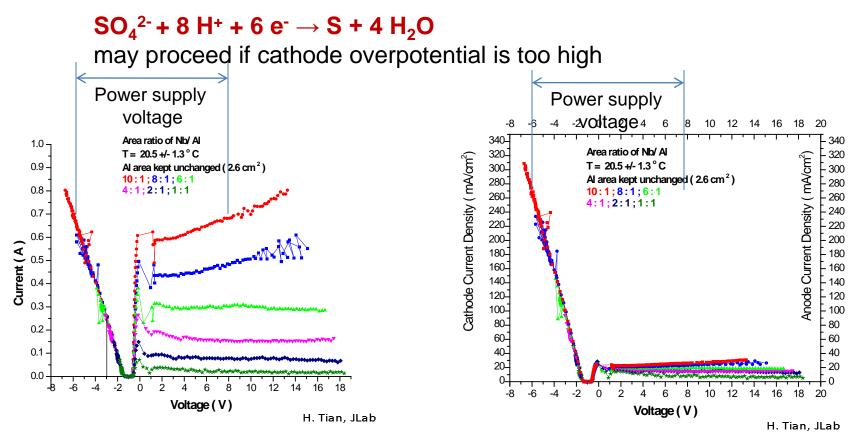
With identical starting topography from CBP, given identical 100 min "EP" at 30°C, single-crystal material was significantly smoother.

Evidence for a significant etching activity at 30°C



Avoid sulfur production at the cathode

- Most electropolishing applications attempt to maximize the surface area of the cathode to avoid process complications (cost).
- In contrast to this, typical horizontal cavity EP circumstances have a cathode:anode active area ratio of 1:10.
- Result is high current density on the cathode and necessary high overpotential to drive the current. *This risks driving other chemistry*.



1:10 HF/H₂SO₄ Electrolyte with Nb

If the objective is maximally smooth surfaces:

Implications:

- We should expect the best micropolishing for topographic features smaller than $^\sim$ 15 μm , so start with surfaces that are consistently smooth to this scale: CBP.
- This process we call "EP" also has a temperaturedependent etching process present, even below 20°C.
 So, minimize the temperature as much as is practical.
- Reduce sulfur production at the cathode by minimizing cathode current density and improving the reaction kinetics for hydrolysis at the cathode.

Contributors

H. Tian JLab, (W&M)

O. Trofimova JLab

M. J. Kelley JLab, W&M, VT

L. Zhao JLab, W&M

S. Corcoran VT

G. Ribeill JLab (DOE SULI)

Key References:

A. J. Bard and L. R. Faulkner, *Electrochemical Methods*, Wiley: New York, 1980.

H. Tian, S. G. Corcoran, C. E. Reece and M. J. Kelley, J. Electrochem. Soc. 155(2008), p. D563.

F F. Éozénou, S. Berry, Y. Gasser, and J-P. Charrier, SRF2009, Berlin, Germany (2009), THPPO069.

V.G. Levich, Physicochemical Hydrodynamics, Prentice-Hall, New York, 1962.

H. Tian, Ph.D. Dissertation, Dept. of Applied Science, College of William and Mary, (2008).

"A Novel Approach to Characterizing the Surface Topography of Niobium Superconducting Radio Frequency (SRF) Accelerator Cavities," H. Tian, C. E. Reece, and M. J. Kelley, Appli. Surf. Sci., (submitted) (2010).

"Evaluation of the diffusion coefficient of fluorine during the electropolishing of niobium" H.Tian and C. E. Reece, PRST-AB, (submitted) (2010).

Authored by Jefferson Science Associates, LLC under U.S. DOE Contract No. DE-AC05-06OR23177.